The NUOVA OFFICINA ASSERGI: future perspectives beyond DarkSide-20k





Overview

- > The NOA Clean Room infrastructure
- Photo-detector packaging machines
- An example of assembling photosensors for a dark matter detector
- > Future plan and perspectives



NOA concept

<u>CIPE</u> - MasterPlan Restart Program of Regione Abruzzo

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@LNGS with 3

main goals

The NOA idea started to be conceived in 2016 and after different phases to achieve the final configuration of room and technical specifications, has turned into reality thanks to the combination of 2 different funds:

<u>PON-MUR</u> Programma Operativo Nazionale-Ministero Università e Ricerca



Realize a photodetector production area equipped with highly sophisticated packaging machines for the assembly of photosensors in a dust controlled environment



Create a dedicated area for assembling large volume detectors



Realize the implementation of a Rn abatement system (CR operating in a Rn free mode)



The first 2 goals have been achieved in the framework of the DarkSide-20k project NOA is an INFN facility managed by LNGS





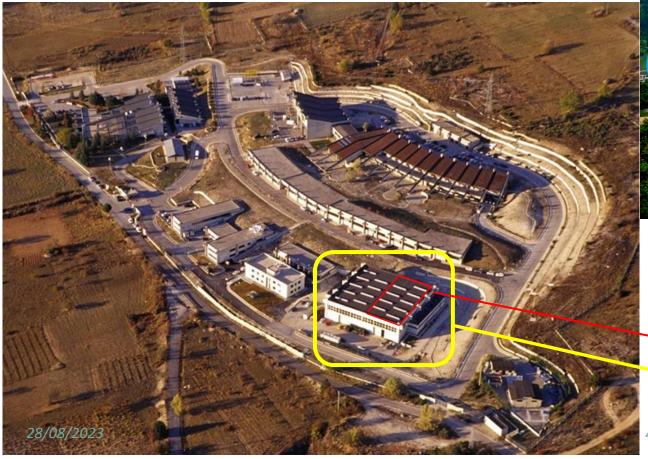






NOA location

LNGS site





NOA occupancy inside **HALL di MONTAGGIO**

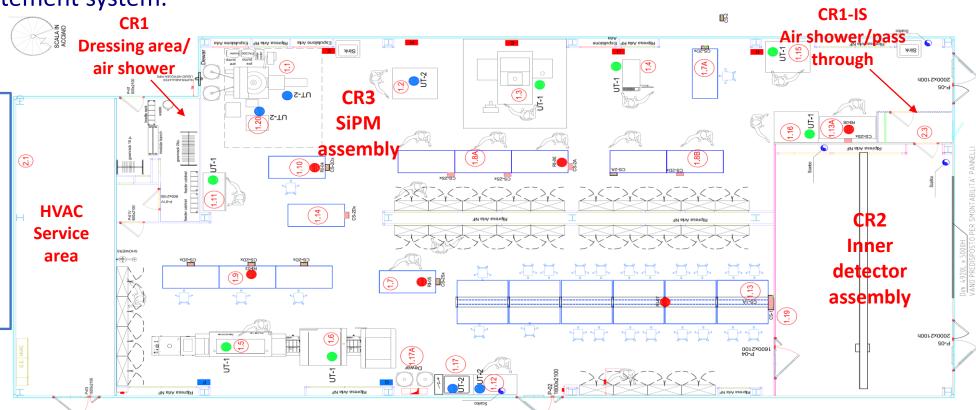


NOA Clean Room layout

- Class ISO 6 with an overall area -> 420 m²
- CR3: 3.0 m high and an area of 353 m²: devoted to the SiPM packaging, test and integration
- CR2: 5.8 m high and an area of 68 m²: devoted to large volume detector assembly
- The design has been conceived in such a way that the air handling system allows to operate CR2 and CR3 separately, both in "normal and " Rn free" mode.

Currently no Rn abatement system.

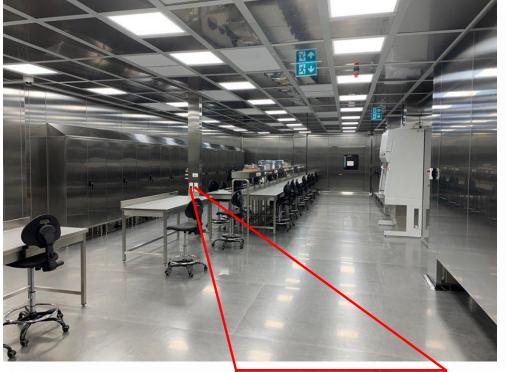
We continuously monitor the Rn concentration in 3 samples points: 2 in CR3 and 1 in CR2. Rn level in CR3 -> 6-10 Bq/m3





NOA configuration

CR3 test & assembly area: 25 workstations



CR3 utilities



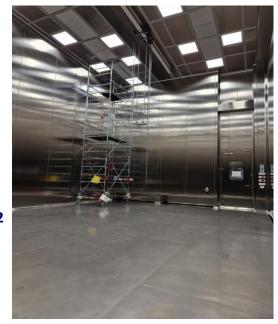
- Liquid nitrogen charging station
- High pressure gas nitrogen
- Industrial water
- Refrigerated water (delivery@ 7°C)
- Deionized water
- Two deionized water sinks
- Two chemical hoods

Workstation utilities



- Electricity (220V, 50Hz) from normal and UPS power supply
- Compressed air
- Low pressure gas nitrogen
- Vacuum
- LAN and telephone lines

CR2
Floor
resistance
2000 kg/m²





NOA packaging area



ADT 7122 DICER



MANUAL
PACKAGING TOOLS:
FRAME MOUNTER
DIE EXPANDER
UV CURING

28/08/2023

INFN Cryoprobe:

a bit of detail

DarkSide-20k Silicon wafer (LFoundry) 200 mm diameter, 550 µm thick; 264 SiPMs to be characterized at cryogenic temperature

magazine

Robot arm

Wafer carrier with

clamp ring

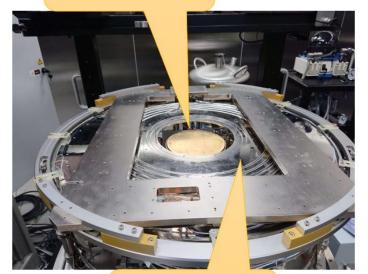


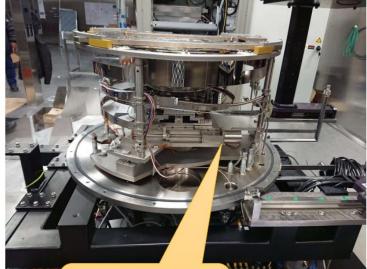
Heater

Gate valve

Chuck







X, Y, Z, theta stepping motors to control the movement of the chuck



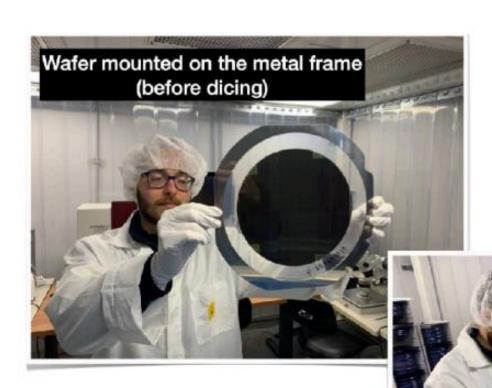
Probe-card
2 x 12 array
of needles
for anode
contacts

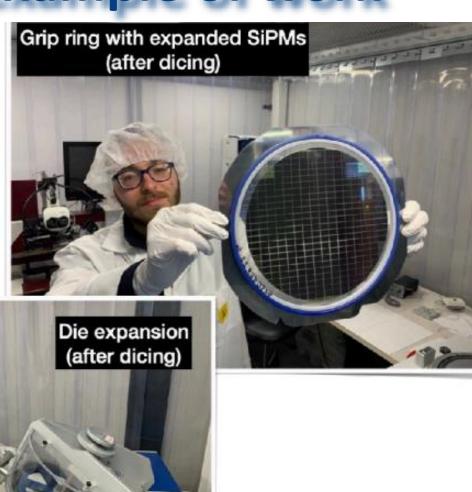
ColdShield

The probe card is fixed above the chuck
The chuck moves up to make "touchdown"



Manual tools: an example of work

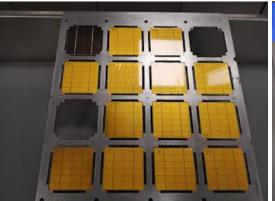




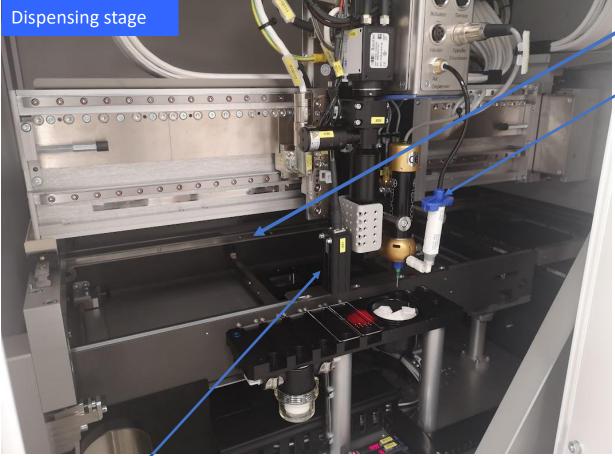
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Flip Chip bonder: pre-process stage



Frame holder for the DarkSide-20k PCBs each one to be assembled with 24 SiPMs

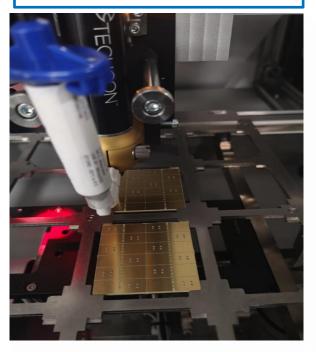


Camera

Conveyor

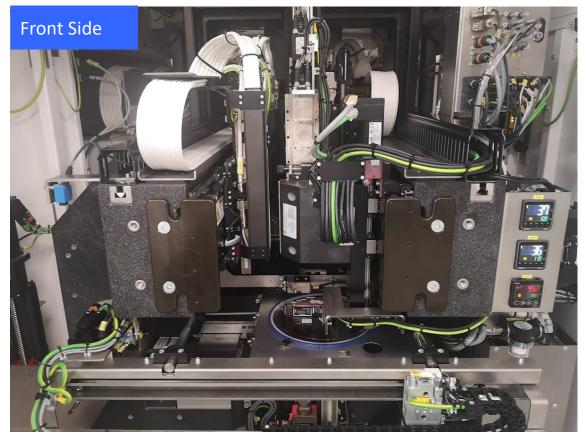
Dispenser

Soldering paste dispensing





Bonding stage

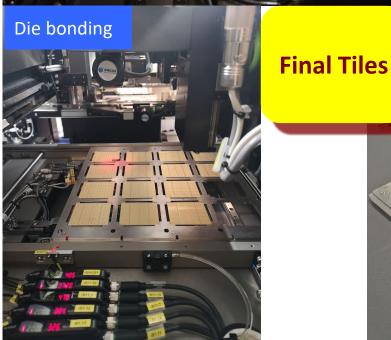


Thermo Compression Bonding: 2 bondheads working in temperature

die size: 11.8 mm x 7.9 mm



Heater plate Max T 350°C

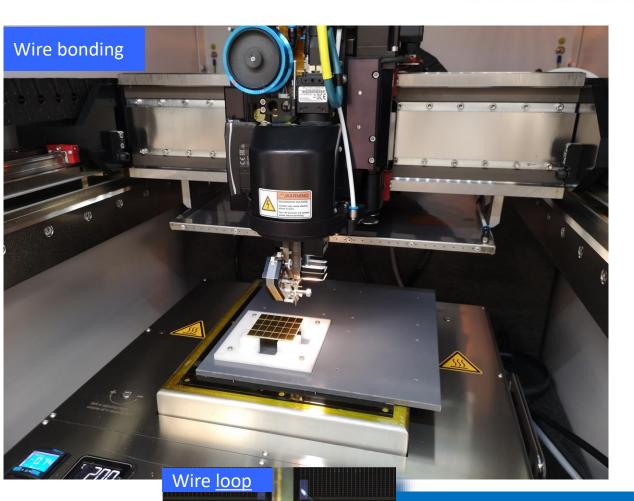


Ready for wire bonding

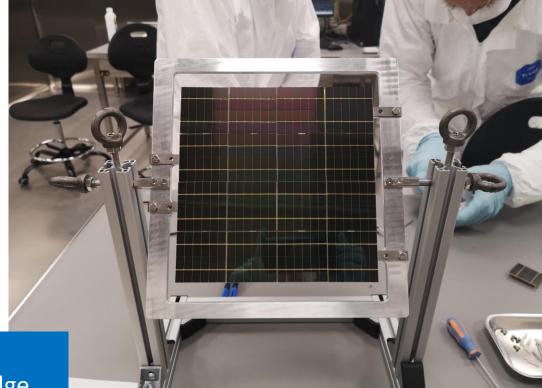
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Wire bonder



DS-20k
Photo Detection
Unit



Bond head BJ855 Ultrasonic wedge-wedge Aluminum wire 25 µm



NOA infrastructure: next plan

- > Optimization of CR operational functions in parallel with the DarkSide-20k activities
- Build a Radon abatement system (1 MEuro estimated cost)
- > Produce a MoU of the infrastructure in agreement with the LNGS Directorate containing:
 - the access rules;
 - operating procedures;
 - technical aspects and plant design of the CR;
 - description of the packaging machines;
 - cost for running and maintenance.

DarkSide-20 people@LNGS

NOA Staff

L. Liberatore, G. Panella, L. Pietrofaccia

Plants/utilities unit

L. Consiglio, D. Sablone

Packaging unit

R. Tartaglia NOA functional unit

V.E. Camillo, A. Flammini, G. Gallina, K.H. Horikawa, G. Korga, A. Marasciulli, P. Organtini

G. Darbo, A. Jamil, S. Minutoli, M.A. Sabia, P. Salomone



Future perspectives - 1

The NOA facility @LNGS is a clean environment devoted to the production and integration of arrays of photodetectors for low background experiments searching for rare events. The infrastructure can be available to all the research communities interested in this kind of technology or in the field of high density interconnections and industrial fields.

The first NOA "customer" is the DarkSide-20k collaboration until end of 2024. The machines have been configured according to the specifications designed by DS-20k but there is enough flexibility of adapting the machines to different needs



Future perspectives - 2

Cryoprobe: different probe-card design/technologies are available on the market; continuous contacts with the companies.

Flip Chip Bonder: it's a high precision die bonder for semiconductor advanced packaging that can maintain a placement accuracy down to $\pm 1\mu m$ @ 3s while bonding with temperatures exceeding 350°C and while also applying high bonding forces (several applications TSV, TCB, 3D IC / 2.5D IC, Flip Chip, Chip on Chip, Chip on Wafer, Chip on Substrate and more...)

Wire Bonder: it is equipped with bond tools for wedge wedge (wire, ribbon) and ball bonding.

We already received requests for the use of the infrastructure by some experimental groups: we are trying to accommodate compatibly with DS-20k activities.

It's IMPORTANT to advertise the facility among the scientific research groups and industries.

We are on the way!